

Title (en)
OPTICAL SYSTEM WITH A HIGH DEGREE OF SYMMETRY

Title (de)
OPTISCHES SYSTEM HOHER SYMMETRIE

Title (fr)
SYSTEME OPTIQUE A DEGRE DE SYMETRIE ELEVE

Publication
EP 0753162 A1 19970115 (DE)

Application
EP 94908267 A 19940223

Priority
DE 9400207 W 19940223

Abstract (en)
[origin: WO9523349A1] The invention concerns an optical system consisting of a lens system (1) in which a diaphragm (2) is located, an image field (3) in which detectors (6) are located and an object field (0), the radii of curvature of the lens system (1), the image field (3) and the object field (0) preferably meeting at a common point which is also the centre of the diaphragm (2). Image-field flattening lenses (7) can be used to flatten the curved image field (3), the flattened image fields lying parallel to planes tangential to the curved image field (3). One or more surfaces of the optical system can be designed as reflecting surfaces (4). An aspherical corrector plate (5) can be inserted into the plane of the diaphragm (2). The light from the curved or flattened image field (3) is fed to the detectors (6) by photoconductive elements (8) which can be displaced with respect to each other and with respect to the image field (3). A preferably afocal ancillary system (9) designed to focus and flatten the image field (3) can be mounted in front of the lens system (1). If the magnification of the ancillary system (9) is variable, the overall focal length of the optical system can also be varied. The image field (3) can be designed as a mirror (10), thus forming a retro-reflector.

IPC 1-7
G02B 3/00

IPC 8 full level
G02B 3/00 (2006.01); **G02B 17/08** (2006.01)

CPC (source: EP)
G02B 3/00 (2013.01); **G02B 6/06** (2013.01); **G02B 13/06** (2013.01); **G02B 27/0025** (2013.01)

Citation (search report)
See references of WO 9523349A1

Designated contracting state (EPC)
CH DE FR GB IT LI

DOCDB simple family (publication)
WO 9523349 A1 19950831; AU 6154094 A 19950911; EP 0753162 A1 19970115; JP H09509265 A 19970916

DOCDB simple family (application)
DE 9400207 W 19940223; AU 6154094 A 19940223; EP 94908267 A 19940223; JP 52204995 A 19940223